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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
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10/827,030

04/19/2004

Joseph M. Torgerson

200210152-1

2745

22879 7590 03/06/2007

HEWLETT PACKARD COMPANY
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EXAMINER

MARTIN, LAURA E

ART UNIT

PAPER NUMBER

2853

SHORTENED STATUTORY PERIOD OF RESPONSE	MAIL DATE	DELIVERY MODE
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3 MONTHS

03/06/2007

PAPER

Please find below and/or attached an Office communication concerning this application or proceeding.

If NO period for reply is specified above, the maximum statutory period will apply and will expire 6 MONTHS from the mailing date of this communication.

Office Action Summary	Application No.	Applicant(s)	
	10/827,030	TORGERSON ET AL.	
	Examiner	Art Unit	
	Laura E. Martin	2853	

-- The MAILING DATE of this communication appears on the cover sheet with the correspondence address --

Period for Reply

A SHORTENED STATUTORY PERIOD FOR REPLY IS SET TO EXPIRE 3 MONTH(S) OR THIRTY (30) DAYS, WHICHEVER IS LONGER, FROM THE MAILING DATE OF THIS COMMUNICATION.

- Extensions of time may be available under the provisions of 37 CFR 1.136(a). In no event, however, may a reply be timely filed after SIX (6) MONTHS from the mailing date of this communication.
- If NO period for reply is specified above, the maximum statutory period will apply and will expire SIX (6) MONTHS from the mailing date of this communication.
- Failure to reply within the set or extended period for reply will, by statute, cause the application to become ABANDONED (35 U.S.C. § 133). Any reply received by the Office later than three months after the mailing date of this communication, even if timely filed, may reduce any earned patent term adjustment. See 37 CFR 1.704(b).

Status

- 1) ☒ Responsive to communication(s) filed on 28 December 2006.
- 2a) ☒ This action is **FINAL**. 2b) ☐ This action is non-final.
- 3) ☐ Since this application is in condition for allowance except for formal matters, prosecution as to the merits is closed in accordance with the practice under *Ex parte Quayle*, 1935 C.D. 11, 453 O.G. 213.

Disposition of Claims

- 4) ☒ Claim(s) 1-50, 56 and 57 is/are pending in the application.
- 4a) Of the above claim(s) 3, 5, 32, 34-42, 45-50 is/are withdrawn from consideration.
- 5) ☐ Claim(s) _____ is/are allowed.
- 6) ☒ Claim(s) 1, 2, 4, 6-31, 33, 43, 44, 56 and 57 is/are rejected.
- 7) ☐ Claim(s) _____ is/are objected to.
- 8) ☐ Claim(s) _____ are subject to restriction and/or election requirement.

Application Papers

- 9) ☐ The specification is objected to by the Examiner.
- 10) ☐ The drawing(s) filed on _____ is/are: a) ☐ accepted or b) ☐ objected to by the Examiner.
Applicant may not request that any objection to the drawing(s) be held in abeyance. See 37 CFR 1.85(a).
Replacement drawing sheet(s) including the correction is required if the drawing(s) is objected to. See 37 CFR 1.121(d).
- 11) ☐ The oath or declaration is objected to by the Examiner. Note the attached Office Action or form PTO-152.

Priority under 35 U.S.C. § 119

- 12) ☐ Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).
- a) ☐ All b) ☐ Some * c) ☐ None of:
1. ☐ Certified copies of the priority documents have been received.
2. ☐ Certified copies of the priority documents have been received in Application No. _____.
3. ☐ Copies of the certified copies of the priority documents have been received in this National Stage application from the International Bureau (PCT Rule 17.2(a)).

* See the attached detailed Office action for a list of the certified copies not received.

Attachment(s)

- | | |
|--|---|
| 1) <input checked="" type="checkbox"/> Notice of References Cited (PTO-892) | 4) <input type="checkbox"/> Interview Summary (PTO-413) |
| 2) <input type="checkbox"/> Notice of Draftsperson's Patent Drawing Review (PTO-948) | Paper No(s)/Mail Date. _____ |
| 3) <input type="checkbox"/> Information Disclosure Statement(s) (PTO/SB/08) | 5) <input type="checkbox"/> Notice of Informal Patent Application |
| Paper No(s)/Mail Date _____ | 6) <input type="checkbox"/> Other: _____ |

DETAILED ACTION

Election/Restrictions

The examiner acknowledges the applicant's traversal to the restriction and will examine upon request claims 1, 2, 4, 6-31, 33, 43, 44, 56, and 57.

Claim Rejections - 35 USC § 102

The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless –

(b) the invention was patented or described in a printed publication in this or a foreign country or in public use or on sale in this country, more than one year prior to the date of application for patent in the United States.

Claims 1, 2, 4, 6, 7, 21-24, 26, 43, 44, 56, and 57 are rejected under 35 U.S.C. 102(b) as being anticipated by Maze et al. (US 20010008411).

Maze et al. disclose the following claim limitations:

As per claim 1: a substrate (figure 3, element 313); a first fluid feed slot formed in the substrate (figure 3, slot at end of opening 307 furthest away from nozzle) and having a first fluid feed slot edge; first firing resistors disposed along the first fluid feed slot and configured to respond to a first current to heat the fluid provided by the first fluid feed slot via a fluid path (figure 3, element 309) and [0032]; a reference conductor formed on the substrate and configured to conduct the first current from the first firing resistors, wherein the reference conductor is disposed under the fluid path in an area between the first fluid feed slot edge and the first firing resistors [0032].

As per claim 2: the reference conductor is disposed between at least two of the firing resistors (figures 3 and 5 – reference conductor has a resistor on one side of it, it would have been obvious to have a resistor on the other side of it, as the nozzles are laid out side by side).

As per claim 4: firing resistor areas disposed along a first fluid feed slot, wherein the reference conductor is disposed between at least two adjacent firing areas (figures 3 and 5 – reference conductor has a resistor on one side of it, it would have been obvious to have a resistor on the other side of it, as the nozzles are laid out side by side).

As per claim 6: drive switches, wherein each drive switch is electrically connected to a corresponding first firing resistor of the first firing resistors and the reference conductor [0030-0032] and (figure 4, elements 401 and 403).

As per claim 7: drive switches, wherein each drive switch is a field effect transistor that is electrically connected between a corresponding first firing resistor and the reference conductor (figure 4, element 403) and [0029-0032].

As per claim 21: vaporization chambers (figure 3, element 301) fluidically coupled to the first fluid feed slot; and an isolation layer configured to isolate the reference conductor from the fluid flowing from the fluid feed slot to the vaporization chambers, wherein the reference conductor is disposed between the vaporization chambers and the first feed slot edge (figure 9, element 907)

As per claim 22: a substrate (figure 3, element 113); a first fluid feed slot formed in the substrate (figure 3, slot at end of opening 307 furthest away from nozzle) and having a first fluid feed slot edge; first vaporization chambers fluidically coupled to the

Art Unit: 2853

first fluid feed slot via a fluid feed path (figure 3, element 301); a reference conductor formed on the substrate and disposed under the fluid path in an area between the first vaporization chambers and the first fluid feed slot edge [0032] and (figures 3, 5, and 9); and an isolation structure configured to isolate the reference conductor from fluid flowing over the first fluid feed slot edge to the first vaporization chambers (figure 9, element 907).

As per claim 23: the reference conductor is disposed between at least two of the vaporization chambers (figures 3 and 5 – reference conductor has a resistor on one side of it, it would have been obvious to have a resistor on the other side of it, as the nozzles are laid out side by side).

As per claim 24: the reference conductor is disposed along to opposing sides of the first fluid feed slot (figure 9, element 503/505).

As per claim 26: each of the fluid paths is fluidically coupled to the first fluid feed slot and an corresponding one of the first vaporization chambers (figure 3) and the reference conductor is isolated from the fluid flowing through the fluid paths by the isolation structure (figure 9, element 907).

As per claim 43: receiving fluid via a fluid path at first firing resistors (figure 3, element 309) disposed along a first fluid feed slot formed in the substrate (figure 3, element 313), the first fluid feed slot having a first fluid feed slot edge (figure 3, slot at end of opening 307 furthest away from nozzle) and the fluid path extending between the first fluid feed slot edge and the first firing resistors (figure 3, element 307), receiving a first current at the first firing resistors; heating the fluid received from the first fluid feed

Art Unit: 2853

slot in response to receiving the first current at the first firing resistors [0032]; receiving the first current from the first firing resistors at a reference conductor (figure 5, elements 503/505) formed on the substrate under the fluid path in an area between the first fluid feed slot edge and the first firing resistor (figure 9); and conducting a first part of the current through the reference conductor as disposed between the first fluid feed slot and the first firing resistors [0032].

As per claim 44: first firing resistor areas (figure 3); conducting a second part of the current through the reference conductor as disposed between the first firing resistor areas [0032].

As per claim 56: a substrate (figure 3, element 313); a first fluid feed slot formed on the substrate (figure 3, slot at end of opening 307 furthest away from nozzle); first vaporization chambers fluidically coupled to the first fluid feed slot via a fluid path (figure 3, element 301); and a reference conductor disposed under the fluid path in an area between the edge of a first fluid feed slot and first vaporization chambers (figures 3 and 5).

As per claim 57: an isolation structure configured to isolate the reference conductor from fluid flowing through the fluid path (figure 9, element 907).

Claims 1, 22, 43, and 56 are rejected under 35 U.S.C. 102(b) as being anticipated by Meyer (US 20020109755).

Meyer discloses the following claim limitations:

As per claim 1: a substrate (figure 1, element 12); a first fluid feed slot formed in the substrate (figure 1, element 16) and having a first fluid feed slot edge; first firing resistors disposed along the first fluid feed slot and configured to respond to a first current to heat the fluid provided by the first fluid feed slot via a fluid path (figure 2, element 38) and [0024]; a reference conductor formed on the substrate and configured to conduct the first current from the first firing resistors, wherein the reference conductor is disposed under the fluid path in an area between the first fluid feed slot edge and the first firing resistors (figure 1, element 40) and [0024].

As per claim 22: a substrate (figure 1, element 12); a first fluid feed slot formed in the substrate (figure 1, element 16) and having a first fluid feed slot edge; first vaporization chambers fluidically coupled to the first fluid feed slot via a fluid feed path (figure 1, element 30); a reference conductor formed on the substrate and disposed under the fluid path in an area between the first vaporization chambers and the first fluid feed slot edge [0024]; and an isolation structure configured to isolate the reference conductor from fluid flowing over the first fluid feed slot edge to the first vaporization chambers (figure 1, element 40).

As per claim 43: receiving fluid via a fluid path at first firing resistors (figure 2, element 38) disposed along a first fluid feed slot formed in the substrate (figure 1, element 12), the first fluid feed slot having a first fluid feed slot edge (figure 1, element 16) and the fluid path extending between the first fluid feed slot edge and the first firing resistors (figure 2, element 38), receiving a first current at the first firing resistors; heating the fluid received from the first fluid feed slot in response to receiving the first

Art Unit: 2853

current at the first firing resistors [0024]; receiving the first current from the first firing resistors at a reference conductor (figure 1, elements 40) formed on the substrate under the fluid path in an area between the first fluid feed slot edge and the first firing resistor (figure 2, element 8); and conducting a first part of the current through the reference conductor as disposed between the first fluid feed slot and the first firing resistors [0024].

As per claim 56: a substrate (figure 3, element 313); a first fluid feed slot formed on the substrate (figure 1, element 16); first vaporization chambers fluidically coupled to the first fluid feed slot via a fluid paths (figure 1, element 14 and 24); and a reference conductor disposed under the fluid path in an area between the edge of a first fluid feed slot and first vaporization chambers (figure 1, element 40).

Claim Rejections - 35 USC § 103

The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negated by the manner in which the invention was made.

Claims 8 and 9 are rejected under 35 U.S.C. 103(a) as being unpatentable over Maze et al. (US 20010008411) in view of Bhaskar et al. (US 5808640).

Maze et al. disclose the following claim limitations:

The device of claim 1.

Maze et al. do not disclose the following claim limitations:

Art Unit: 2853

As per claim 8: the reference conductor is disposed along the entire length of the fluid feed slot.

As per claim 9: the reference conductor is disposed along opposing sides of the first fluid feed slot and along the entire length of the opposing sides of the first fluid feed slot.

Bhaskar et al. disclose the following claim limitations:

As per claim 8: the reference conductor is disposed along the entire length of the fluid feed slot (figure 5, elements 64, 66, 68, and 70).

As per claim 9: the reference conductor is disposed along opposing sides of the first fluid feed slot and along the entire length of the opposing sides of the first fluid feed slot (figure 5, elements 64, 66, 68, and 70).

It would have been obvious to one of ordinary skill in the art at the time of the invention to modify the fluid ejection device taught by Maze et al. with the disclosure of Bhaskar et al. in order to provide a higher quality ink ejection device.

Claims 10-19, 25, 27-31, and 33 are rejected under 35 U.S.C. 103(a) as being unpatentable over Maze et al. (US 20010008411) in view of Cleland et al. (US 6491377).

Maze et al. disclose the following claim limitations:

As per claims 10-19, the reference conductor (figure 5, element 505/503) being configured to conduct current [0032] to a resistor (figure 5, element 501), wherein the

Art Unit: 2853

reference conductor is disposed between the first fluid feed source edge (and the firing resistors (figures 3, 5, and 9).

As per claims 25 and 29: a reference conductor (figure 5, element 503/505) disposed between a fluid vaporization chambers and the first fluid feed source (figures 3 and 5).

As per claim 26: the reference conductor is isolated from fluid flowing through the fluid paths by the isolation structure (figure 9, element 907)

As per claim 27: the second vaporization chambers and the second fluid feed source edge and the isolation structure is configured to isolate the reference conductor from fluid flowing over the second fluid feed source edge to the second vaporization chambers (multiple cartridges (figure 1, element 111) mean multiple vaporization chambers, figure 9, element 907).

As per claim 28: the reference conductor is (figure 5, element 503/505) disposed between at least two of the second vaporization chambers (figures 3, 5, and 9).

As per claim 31: drive switches, wherein each of the drive switches is electrically coupled between a corresponding one of the firing resistors and the reference conductor (figure 4, elements 401/403) and [0030-0032].

Maze et al do not disclose:

As per claim 10, the first firing resistors are disposed along opposing sides of the first fluid feed source.

As per claim 11, second firing resistors disposed along the first fluid feed source and configured to respond to a second current to heat fluid provided by the first fluid feed source.

As per claim 12 the second firing resistors are disposed on opposing sides of the first fluid feed source.

As per claim 13, a second fluid feed source and third firing resistors disposed along the second fluid feed source and configured to respond to a third current to heat fluid provided by the second fluid feed source.

As per claim 14, the third firing resistors are disposed on opposing sides of the second fluid feed source and a third fluid feed source edge along another one of the opposing sides of the second fluid feed source.

As per claim 15, fourth firing resistors disposed along the second fluid feed source and configured to respond to a fourth current to heat fluid provided by the second fluid feed source.

As per claim 16, the fourth firing resistors are disposed on opposing sides of the second fluid feed source.

As per claim 17, fifth firing resistors, wherein a first portion of the fifth firing resistors are disposed along the first fluid feed source and configured to respond to a fifth current to heat fluid provided by the first fluid feed source and a second portion of

the fifth firing resistors are disposed along the second fluid feed source and configured to respond to the fifth current to heat fluid provided by the second fluid feed source.

As per claim 18, sixth firing resistors, wherein a first portion of the sixth firing resistors are disposed along the first fluid feed source and configured to respond to a sixth current to heat fluid provided by the first fluid feed source and a second portion of the sixth firing resistors are disposed along the second fluid feed source and configured to respond to the sixth current to heat fluid provided by the second fluid feed source.

As per claim 19, a second fluid feed source having a second fluid feed source edge in communication with the substrate surface and second firing resistors, wherein a first portion of the second firing resistors are disposed along the first fluid feed source and configured to respond to a second current to heat fluid provided by the first fluid feed source and a second portion of the second firing resistors are disposed along the second fluid feed source and configured to respond to the second current to heat fluid provided by the second fluid feed source.

As per claim 25, the first vaporization chambers are disposed along opposing sides of the first fluid feed source and the reference conductor is disposed between the first vaporization chambers and the first fluid feed source edge along one of the opposing sides of the first fluid feed source and the first vaporization chambers and a second fluid feed source edge along another one of the opposing sides of the first fluid feed source.

As per claim 26, fluid paths, wherein each of the fluid paths is fluidically coupled to the first fluid feed source and a corresponding one of the first vaporization chambers

Art Unit: 2853

and the reference conductor is isolated from fluid flowing through the fluid paths by the isolation structure.

As per claim 27, a second fluid feed source having a second fluid feed source edge; and second vaporization chambers fluidically coupled to the second fluid feed source.

As per claim 28, the reference conductor is disposed between at least two of the second vaporization chambers.

As per claim 29, the second vaporization chambers are disposed along opposing sides of the second fluid feed source and the reference conductor.

As per claim 30, firing resistors, wherein each of the firing resistors is disposed in a corresponding one of the first vaporization chambers and configured to respond to a current to heat fluid provided by the first fluid feed source and the reference conductor is configured to conduct the current from the firing resistors.

Cleland et al. disclose the following claim limitations:

As per claim 10, the first firing resistors are disposed along opposing sides of the first fluid feed source (figure 13A, element 9-10 MAGENTA) and the reference conductor (figure 11C, element 1111) is disposed between the first firing resistors and the first fluid feed source edge along one of the opposing sides of the first fluid feed source and the first firing resistors and a second fluid feed source edge along another one of the opposing sides of the first fluid feed source.

As per claim 11, second firing resistors disposed along the first fluid feed source and configured to respond to a second current to heat fluid (column 15, line 64-column 16, line 23) provided by the first fluid feed source (figure 13A, elements 13-14, MAGENTA).

As per claim 12 the second firing resistors are disposed on opposing sides (figure 13A, element 13-14) of the first fluid feed source.

As per claim 13, a second fluid feed source and third firing resistors disposed along the second fluid feed source (figure 13A, element CYAN 17-20) and configured to respond to a third current to heat fluid (column 15, line 64-column 16, line 23) provided by the second fluid feed source.

As per claim 14, the third firing resistors are disposed on opposing sides of the second fluid feed source (figure 13A, element CYAN 17-20).

As per claim 15, fourth firing resistors disposed along the second fluid feed source (figure 13A, element 21-24 CYAN) and configured to respond to a fourth current to heat fluid provided by the second fluid feed source (column 15, line 64-column 16, line 23).

As per claim 16, the fourth firing resistors are disposed on opposing sides of the second fluid feed source (figure 13A, element CYAN).

As per claim 17, fifth firing resistors, wherein a first portion of the fifth firing resistors are disposed along the first fluid feed source (figure 13A, MAGENTA 15 and 16) and configured to respond to a fifth current to heat fluid provided by the first fluid feed source (column 15, line 64-column 16, line 23) and a second portion of the fifth

Art Unit: 2853

firing resistors are disposed along the second fluid feed source and configured to respond to the fifth current to heat fluid provided by the second fluid feed source (column 15, line 64-column 16, line 23).

As per claim 18, sixth firing resistors, wherein a first portion of the sixth firing resistors are disposed along the first fluid feed source (figure 13A, element MAGENTA 9-10) and configured to respond to a sixth current to heat fluid provided by the first fluid feed source (column 15, line 64-column 16, line 23) and a second portion of the sixth firing resistors are disposed along the second fluid feed source and configured to respond to the sixth current to heat fluid provided by the second fluid feed source (column 15, line 64-column 16, line 23).

As per claim 19, a second fluid feed source having a second fluid feed source edge (figure 13A, element CYAN) in communication with the substrate surface (figure 13A, 1300) and second firing resistors (figure 13A, element 13-16), wherein a first portion of the second firing resistors are disposed along the first fluid feed source and configured to respond to a second current to heat fluid provided by the first fluid feed source and a second portion of the second firing resistors are disposed along the second fluid feed source and configured to respond to the second current to heat fluid provided by the second fluid feed source (column 15, line 64-column 16, line 23).

As per claim 25, the first vaporization chambers (column 1, line 61-column 2, line 5) are disposed along opposing sides of the first fluid feed source (figure 13A, CYAN, 9-12) and the reference conductor (figure 11A, element 1111) is disposed between the first vaporization chambers and the first fluid feed source edge along one of the

Art Unit: 2853

opposing sides of the first fluid feed source and the first vaporization chambers and a second fluid feed source edge along another one of the opposing sides of the first fluid feed source.

As per claim 26, fluid paths, wherein each of the fluid paths is fluidically coupled to the first fluid feed source and a corresponding one of the first vaporization chambers (column 12, lines 54-62)

As per claim 27, a second fluid feed source having a second fluid feed source edge; and second vaporization chambers fluidically coupled to the second fluid feed source (figure 13A, element MAGENTA, 9-16)

As per claim 29, the second vaporization chambers are disposed along opposing sides of the second fluid feed source (figure 13A, elements MAGENTA 17-20) and the reference conductor (figure 11A, element 1111).

As per claim 30, firing resistors, wherein each of the firing resistors is disposed in a corresponding one of the first vaporization chambers (column 1, line 61-column 2, line 5) and configured to respond to a current to heat fluid provided by the first fluid feed source and the reference conductor is configured to conduct the current from the firing resistors (column 15, line 64-column 16, line 23).

It would have been obvious to one of ordinary skill in the art at the time of the invention to modify the fluid ejection device of Maze et al. with the disclosure of Cleland et al. in order to create a higher quality printer.

Claim 20 is rejected under 35 U.S.C. 103(a) as being unpatentable over Maze et al. (US 20010008411) in view of Chen et al. (US 20020135640).

Maze et al. disclose the following claim limitations:

The device of claim 1.

Maze et al. do not disclose the following claim limitations:

The reference conductor comprises a conductive layer and a resistive layer.

Chen et al. do not disclose the following claim limitations:

The reference conductor comprises a conductive layer and a resistive layer
[0024].

It would have been obvious to one of ordinary skill in the art at the time of the invention to modify the fluid ejection device of Maze et al. with the disclosure of Chen et al. in order to create a higher quality printer.

Response to Arguments

Applicant's arguments with respect to claims 1-50, 56, and 57 have been considered but are moot in view of the new ground(s) of rejection.

Conclusion

Applicant's amendment necessitated the new ground(s) of rejection presented in this Office action. Accordingly, **THIS ACTION IS MADE FINAL**. See MPEP

Art Unit: 2853

§ 706.07(a). Applicant is reminded of the extension of time policy as set forth in 37 CFR 1.136(a).

A shortened statutory period for reply to this final action is set to expire THREE MONTHS from the mailing date of this action. In the event a first reply is filed within TWO MONTHS of the mailing date of this final action and the advisory action is not mailed until after the end of the THREE-MONTH shortened statutory period, then the shortened statutory period will expire on the date the advisory action is mailed, and any extension fee pursuant to 37 CFR 1.136(a) will be calculated from the mailing date of the advisory action. In no event, however, will the statutory period for reply expire later than SIX MONTHS from the date of this final action.

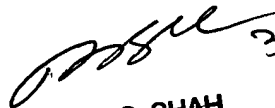
Any inquiry concerning this communication or earlier communications from the examiner should be directed to Laura E. Martin whose telephone number is (571) 272-2160. The examiner can normally be reached on Monday - Friday, 7:00 - 3:30.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Stephen D. Meier can be reached on (571) 272-2149. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

Art Unit: 2853

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see <http://pair-direct.uspto.gov>. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free). If you would like assistance from a USPTO Customer Service Representative or access to the automated information system, call 800-786-9199 (IN USA OR CANADA) or 571-272-1000.

Laura E. Martin

 3/5/07
MANISH S. SHAH
PRIMARY EXAMINER